

3D Contact Profilometer

Manufacturer: [AEP Technology](#)

Model: [500LS](#)



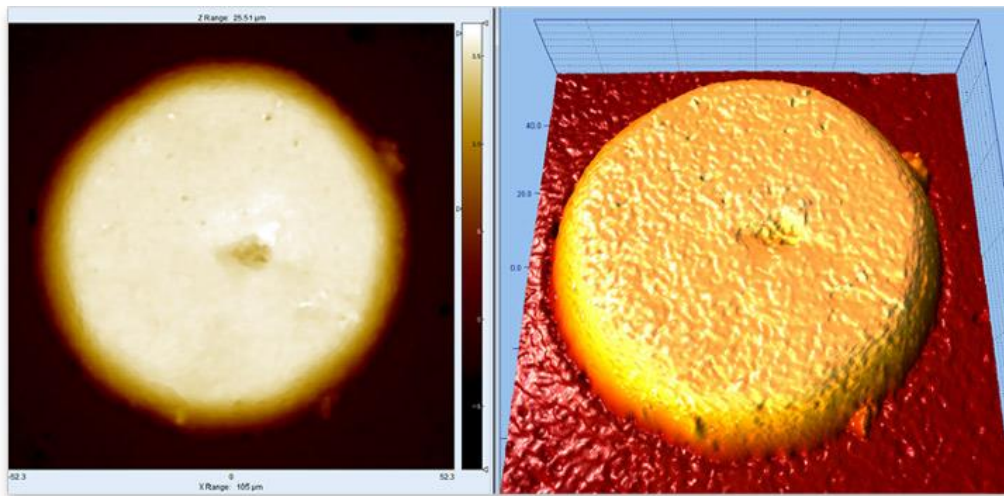
Descriptions:

NanoMap-LS allows for both tip and stage scan modes. Tip scan uses piezo drive to move the stylus up to 500x500micron area and generates ultra high resolution image. Stage scan moves the sample stage to generate high resolution image. As piezo stage has better XY accuracy tip scan produces far better image as compared to stage scan mode. With a click of button tip and stage scan modes can be selected on NanoMap-LS

Features:

Vertical Resolution	0.1 nm (tip dependent)
Vertical Dynamic Range	Up to 5 um with fine range; up to 1300 um with high range
Scan Range	Up to 150 mm x 150 mm (upgrade available)
XY Piezo Stage Resolution	0.1um;
Stylus Loading Force	0.03 mg to 100 mg
Optical Camera Color camera	1.5 x 1.5 mm FOV
Illumination Bright and dark field	SW settable intensity

HD Images (2D and 3D)



Applications:

- Step heights measurement
- Surface Roughness measurement
- Quantify scratch and dig features, wear depth, width and volume
- Flatness or curvature measurement
- 2D thin film stress measurement
- Film thickness
- Surface Profiling - defect, features etc